

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: **Davis, et al.**

Serial No.: **10/628,001**

Examiner: **Stevenson, Andre C.**

Confirmation No.: **3943**

**Title: METHOD FOR AUTOMATIC
DETERMINATION OF
SEMICONDUCTOR PLASMA
CHAMBER MATCHING AND
SOURCE OF FAULT BY
COMPREHENSIVE PLASMA
MONITORING**

§ Case: **AMAT/7938/ETCH/SILICON/JB**

§ Filed: **July 25, 2003**

§ Group Art Unit: **2812**

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S I R:

RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 10, 2006

In response to the Final Office Action dated February 10, 2006, having a shortened statutory period for response set to expire on May 10, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no fee is due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.